

Korean International Semiconductor Conference & Exhibition on Manufacturing Technology 2025

KISM 2025 BUSAN

Re:Innovation of Semiconductor Manufacturing for AI Ecosystem

| [ThF2] Carbon | Neutrality in Semiconductor Industry II |
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Session Date November 13 (Thu.), 2025

Session Time 10:50-12:25

Session Room F (Panorama Room, 16F)

[ThF2-1] [Invited] 10:50-11:15

Development of NF₃ Alternative Gas for Global Warming Potential Reduction

Wontae Noh, Woongbin Yim, Soo Namgoong, Sukhyun Hong, Sung Ryong Moon, Sangmin Lee, and Young Chul Choi (Wonik IPS, Korea)

[ThF2-2] [Invited] 11:15-11:40

Improvement of PFC Gas Treatment Technology for Etching Using Catalysts and Its Additional Effects

Yongjin Kim, Sangyoon Kim, and Jongpil Yoon (ECO ENERGEN Co., Ltd., Korea)

[ThF2-3] [Invited] 11:40-12:05

Case Study on the Demonstration of a White Plume Reduction Device (K-Industry)

Sang Woo Lee, Hyeong Kee Lee, and Seung Han Kwon (NURI PLAN Co., Ltd., Korea)

[ThF2-4] 12:05-12:25

Low Temperature Etching of SiO_2 and Si_3N_4 Using Low Global Warming C_3F_6 , C_3HF_5 , and $C_3H_2F_4$

Sumin Park, Daeun Hong, Eunsu Lee, Minsung Jeon, and Heeyeop Chae (Sungkyunkwan Univ., Korea)